Special Issue

State-of-the-Art CMOS and MEMS Devices

Message from the Guest Editor

CMOS and MEMS devices act as significant roles in the emerging research fields, such as artificial intelligence (AI), 5G communication, and medical electronics. With the continuous development of material science and micro-fabrication processes, high-performance CMOS and MEMS devices are widely investigated and have achieved great progresses. Recently, the rapid development of heterogeneous integration and complex multi-functional systems has put forward higher requirements for CMOS and MEMS Devices, and it is urgent to develop novel CMOS and MEMS devices utilizing advanced materials, techniques, and processes. Thus, in this Special Issue, we invite authors to report the state-of-the-art designs, modeling, fabrication, and applications of CMOS and MEMS devices. The potential topics include, but are not limited to the developments of advanced CMOS devices, CMOS integrated circuits, MEMS devices, 3D integration technology, flexible devices, etc.

Guest Editor

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